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EOT/Rachet
Y Robinson
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00862.022205.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Yoshiyuki NAGAI et al.

Application No.: 09/839,139

Filed: April 23, 2001

For: LASER OSCILLATION APPARATUS, EXPOSURE
APPARATUS, SEMICONDUCTOR DEVICE
MANUFACTURING METHOD, SEMICONDUCTOR
MANUFACTURING FACTORY, AND EXPOSURE
APPARATUS MAINTENANCE METHOD

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: Examiner: M. Landau

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: Group Art Unit: 2815

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:
: April 17, 2003

The Commissioner for Patents
Washington, D.C. 20231

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TECHNOLOGY CENTER 2800

AMENDMENT WITH PETITION FOR EXTENSION OF TIME

Sir:

Applicants petition the Commissioner for Patents to extend the time for response to the Office Action dated December 17, 2002, for one month from March 17, 2003, up to and including April 17, 2003. A check in the amount of \$110.00 for payment of the extension fee is enclosed. Please charge any additional fee required for the extension, or credit any overpayment, to Deposit Account 06-1205.

INTRODUCTORY COMMENTS

This Amendment has been prepared in accordance with the Revised Format established by the U.S. Patent and Trademark Office, as permitted in the Pre-OG Notice dated February 4, 2003, and entitled "Amendments in a Revised Format Now Permitted."

In response to the Official Action dated December 17, 2002, please amend the above-identified application as follows: